

Resource Summary Report

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UC Berkeley Marvell Nanofabrication Laboratory

RRID:SCR_012246

Type: Tool

Proper Citation

UC Berkeley Marvell Nanofabrication Laboratory (RRID:SCR_012246)

Resource Information

URL: <http://www.scienceexchange.com/facilities/marvell-nanofabrication-laboratory, micro/nanoelectromechanical systems, microelectronics>

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Description: The Marvell Nanofabrication Laboratory at the University of California, Berkeley is a multidisciplinary facility that serves research and education in the areas of integrated circuits (ICs) and systems, micro/nanofabrication technologies, micro/nanoelectromechanical (MEMS/NEMS) systems, advanced materials and interdisciplinary applications of microelectronics. This facility offers processing for both 4 inch and 6 inch substrates (wafers).

Synonyms: University of California Berkeley Marvell Nanofabrication Laboratory

Resource Type: access service resource, service resource, core facility

Keywords: integrated circuits, micro/nanofabrication technology,

Resource Name: UC Berkeley Marvell Nanofabrication Laboratory

Resource ID: SCR_012246

Alternate IDs: SciEx_10987

Record Creation Time: 20220129T080309+0000

Record Last Update: 20260729T044301+0000

Ratings and Alerts

No rating or validation information has been found for UC Berkeley Marvell Nanofabrication Laboratory.

No alerts have been found for UC Berkeley Marvell Nanofabrication Laboratory.

Data and Source Information

Source: [SciCrunch Registry](#)

Usage and Citation Metrics

We found 1 mentions in open access literature.

Listed below are recent publications. The full list is available at [nidm-terms](#) .

Friedman AD, et al. (2017) The Young Innovators Program at the Eshelman Institute for Innovation: a case study examining the role of a professional pharmacy school in enhancing STEM pursuits among secondary school students. International journal of STEM education, 4(1), 17.